

Annual Report of an ANSI/OEOSC TAG to ISO TC172 Subcommittee Covering the Year 2016

TAG Subcommittee Number and Name: SC1 Fundamental Standards

TAG Subcommittee Leader: Dave Aikens

ISO Meetings Held During 2016

Subcommittee meetings usually include break-out meetings of working groups and project groups. List the top-level meeting; do not list the break-out meetings.

Subcommittee, Working, or Project Group Meeting Name	Date(s)	Location
TC172 SC1	10/10-10/12/16	Bucharest, Romania

ISO Meetings Scheduled for 2017

Subcommittee meetings usually include break-out meetings of working groups and project groups. List the top-level meeting; do not list the break-out meetings.

Subcommittee, Working, or Project Group Meeting Name	Date(s)	Location
TC172 SC1	October 23-27	Tokyo, JP

Significant Accomplishments in 2016

ISO Subcommittee

SC1 continues to enjoy a significant and increasing presence from China, and retains strong participation from Japan, Germany and the United States. As a result, the work program has been moving at an excellent pace. In 2016 we published five standards, including revisions to parts 9 and 11 of our flagship standard series, ISO 10110 the

international drawing standard for optics. We have also conducted systematic review and approval of another seven standards, and made extensive progress on our work program, including a suite of standards regarding surface imperfections, which have advanced together to the FDIS stage. The minor revision of two parts passed the CD stage. Two other massive projects also passed the CD stage; ISO 10110-1 which merges ISO 10110 part 10 to part 1 and expands the general drawing format substantially, and ISO 10110-18 which merges ISO 10110 parts 2, 3, and 4 and expands their application to raw optical glass. A revision to ISO 10110 part 8 has been approved at the WD level. Finally one new PWI was approved, for spectroscopic measurements of scattered light.

US TAG Subcommittee

The SC1 part of the US TAG continues to gain bench strength, with 28 experts in the sub-committee, including seven very active members, five of whom attended the annual meeting. The strong representation allowed us to participate fully in all WG meetings.

In addition, the US continues to be very active in the work of the subcommittee, with experts participating in all of the projects within all three WG's. US Experts are currently leading seven active projects.

One of our greatest accomplishments this year was to advance the revisions to the surface imperfections part of ISO 10110 and its sister standards to the FDIS stage. These standards now include incorporation of the US industry standard methods for specifying and evaluating surface imperfections based on the ANSI scratch and dig method. Another great accomplishment has been to move the new standard ISO 10110 part 18 to the CD level. This important standard will fix the most glaring errors in the materials specification parts of ISO 10110, as well as allow a material certification method which is common practice in US industry and throughout the world.

Significant Problems Encountered in 2016

ISO Subcommittee

There have been no significant barriers to our work in the ISO subcommittee beyond the usual differences of opinion of the delegations rising from differing standard practice within countries.

US TAG Subcommittee

There are no issues for the TAG at this time.

Projections for 2017

ISO Subcommittee

We will continue to advance the revisions to ISO 10110, specifically with changes to material specifications (part 18), surface imperfections (part 7), surface texture (part 8) and general drawing formats (part 1).

TAG Subcommittee

Continue to maintain consensus for our core objectives of bringing US standard practice into the ISO 10110 family of standards.